

Request for Tenders under Open (OJEU) Procedure for the Supply, Delivery and Installation of a Broad Ion Beam Milling System for SP&S for the Tyndall National Institute, UCC

Detailed description:

The Specialty Products & Services Group (SP&S) at Tyndall National Institute, UCC, fabricate a wide variety of Semiconductor devices, ranging from traditional Silicon microelectronics and Silicon MEMS to III-V photonic devices. In addition, SP&S provide an extensive array of analysis services in all types of electronic devices and packages to internal and external customers. The Electron Microscopy and Analysis Facility (EMAF) within SP&S utilise a wide range of SEM, TEM and FIB equipment as part of these analysis services. We wish to extend our capability in the area of sample preparation by purchasing a fully functional Broad Ion Beam (BIB) milling system with an ancillary mechanical polishing system which will allow us to bridge a sample cross-section preparation gap between our existing plasma FIB and mechanical methods

Type of contract:

Supplies

Response deadline (Irish time):

10/05/2022 12:00:00

CPV codes:

39300000-5 Miscellaneous equipment

38000000-5 Laboratory, optical and precision equipments (excl. glasses)

73110000-6 Research services

73111000-3 Research laboratory services